



Update on Technology Transfer of high rate µ-RWELL

Matteo Giovannetti [LNF-INFN]

on behalf of LNF-INFN (leading group) Bologna-Ferrara INFN teams R. De Oliveira – CERN-EP-DT-MPT Workshop R. Pinamonti, M. Pinamonti – ELTOS S.p.A.

RD51 - WG6, CERN, Dec. 6th 2023

This research has been supported by the E.U. Project AIDAInnova Task 7.3 (European Union's Horizon 2020 Research and Innovation programme, grant agreement N.101004761)

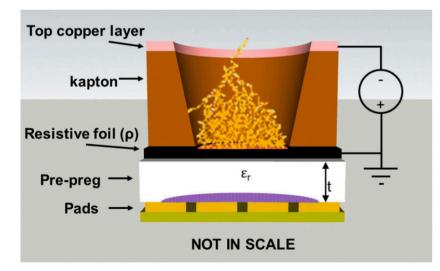
L2=101.71u

13=55 140

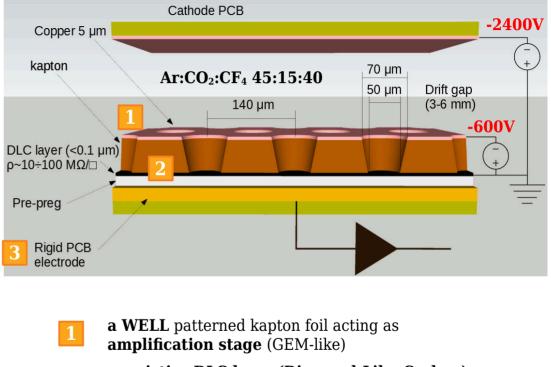
L7=48,18µr

The µ-RWELL detector [reminder]

The μ -RWELL is a Micro Pattern Gaseous Detector (MPGD) composed of only two elements: the μ -RWELL_PCB and the cathode. **The core is the \mu-RWELL_PCB**, realized by coupling three different elements:



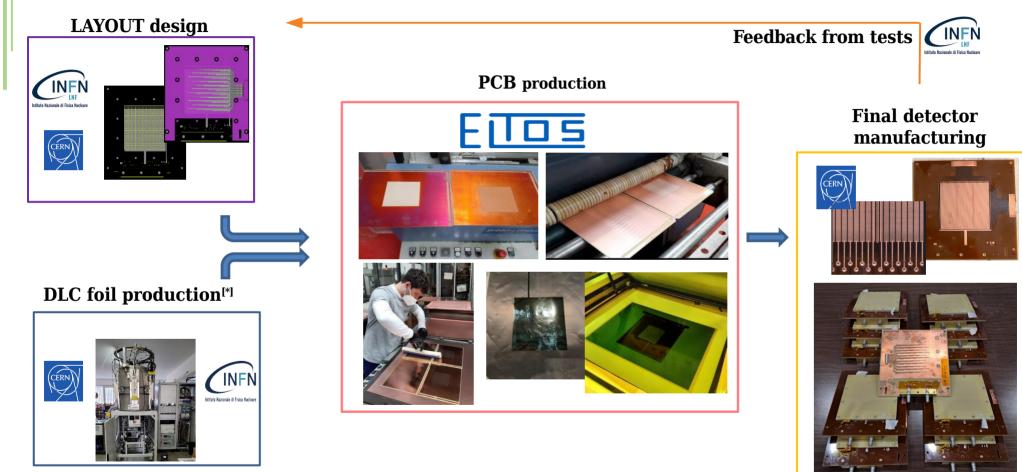
Applying a suitable voltage between the **top Cu-layer and the DLC** the WELL acts as a **multiplication channel for the ionization** produced in the conversion/drift gas gap.



- a **resistive DLC layer (Diamond-Like-Carbon)** for discharge suppression with surface resistivity $\sim 50 \div 100 \text{ M}\Omega/\Box$
- a standard readout PCB

µ-RWELL Technology Transfer [flow chart]





[*] DLC Magnetron Sputtering machine co-funded by INFN- CSN1

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µ-RWELL Technology Transfer 2023



FILOS

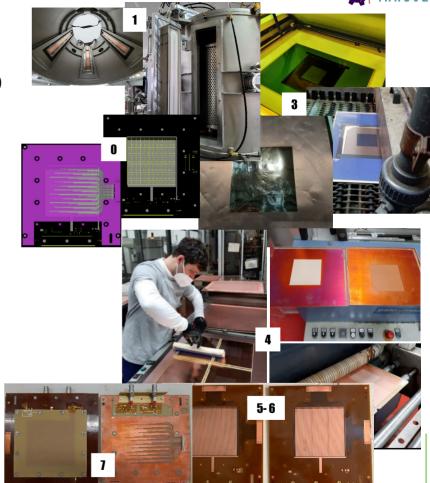
INFN

Step 0 - Detector PCB design @ LNF + CERN-MPT

Step 1 - CERN_INFN **DLC sputtering machine** @ CERN (+INFN)

- In operation since Nov. 2022
- Production by LNF-INFN crew





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Step 2 – Producing readout PCB by ELTOS

• pad/strip readout



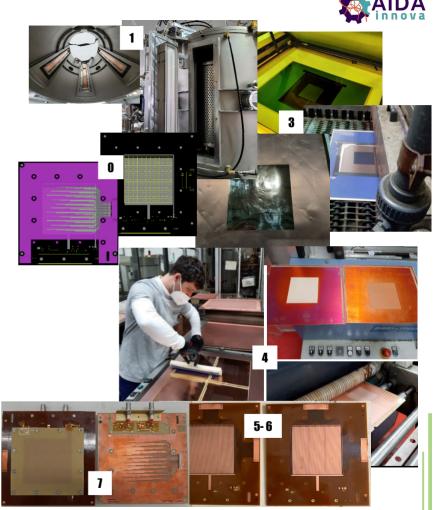
INFN

Step 3 - **DLC patterning** by ELTOS

photo-resist \rightarrow patterning with BRUSHING-machine

Step 4 - **DLC foil gluing** on PCB by ELTOS

Large press available, up to 16 PCBs workable at the same time



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µ-RWELL Technology Transfer 2023



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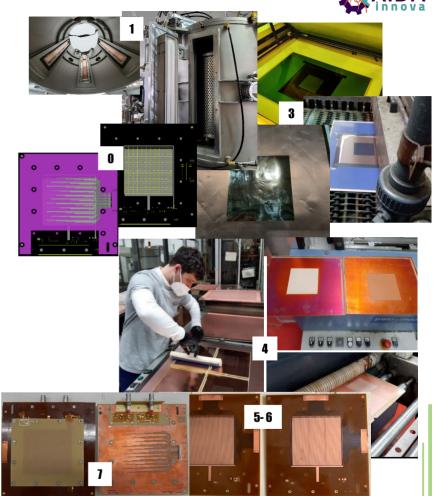
Step 5 - Ground network connections creation by CERN

PEP layout: Cu **P**atterning \rightarrow PI **E**tching \rightarrow Cu **P**lating

Step 6 - Amplification stage patterning by CERN

- Cu amplification holes image and HV connections by Cu etching
- PI etching \rightarrow plating \rightarrow amplification-holes

Step 7 - Electrical cleaning and detector closing @ CERN



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High-rate layout optimisation

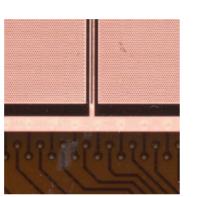


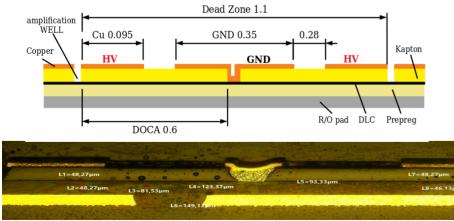
The GOAL: **minimizing** the average **path towards the ground** connection by introducing a **high-density grounding network** on the DLC layer. In **PEP** (Patterning-Etching-Plating) layouts the top Cu layer is connected to the DLC, plating through the APICAL foil.



DLC grounding by **conductive groove** Pad R/O = 9×9 cm² Grounding: - pitch = 9.0 mm - width = 1.1 mm

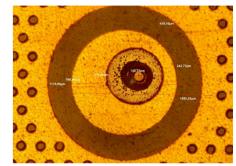
 \rightarrow 84% geometric acceptance



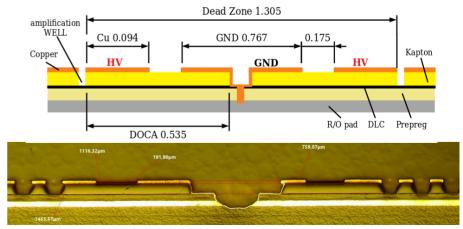




DLC grounding by **conductive DOT** Pad R/O = $9 \times 9 \text{cm}^2$ Grounding: - pitch = 9.0 mm - rim = 1.3 mm



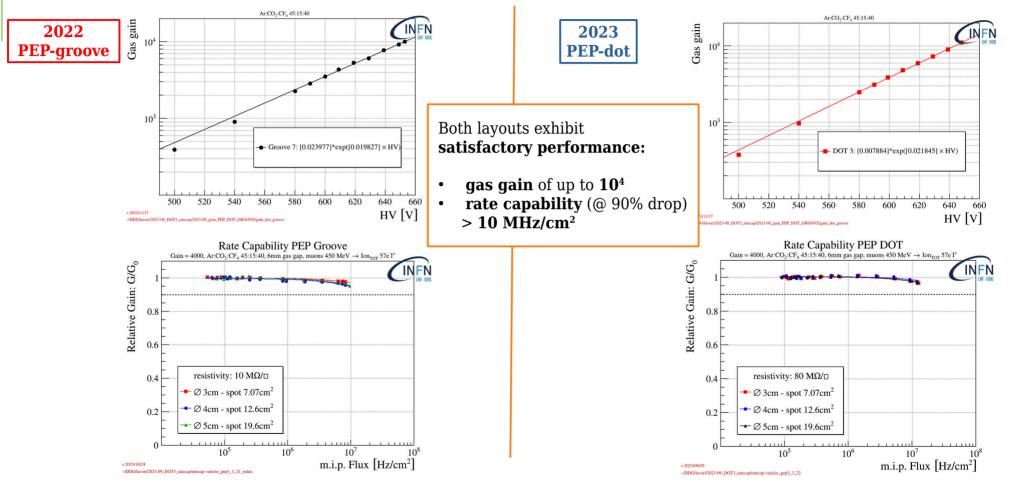
 \rightarrow 97% geometric acceptance



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High-rate layout optimisation

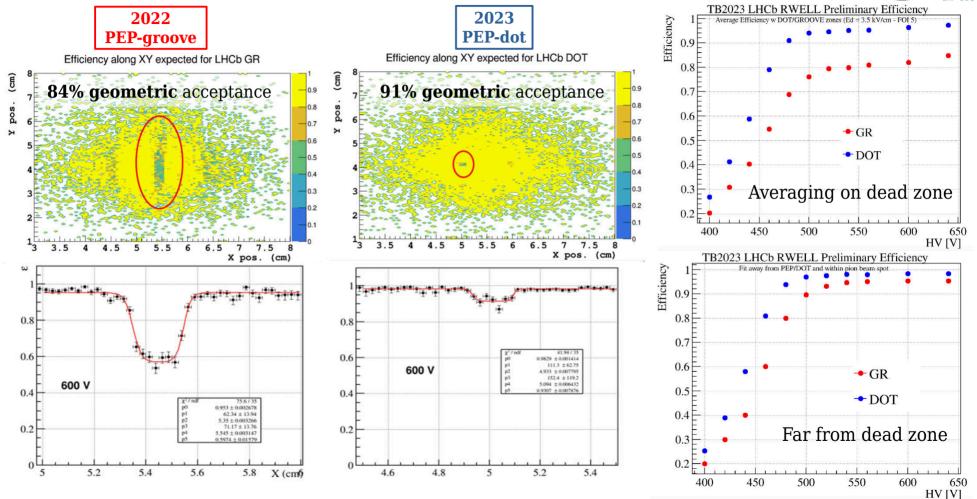




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BT'23 [APV25]: Groove-DOT layouts comparison





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The CERN-INFN DLC machine

 $\begin{array}{l} \textbf{31^{st} Oct. 2022 - Delivered} \\ \textbf{31^{st} Oct. - 4^{th} Nov. 2022 - Commissioning & test training \\ \textbf{21^{st} - 23^{rd} Nov. 2022 - 1^{st} DLC sputtering test} \\ & Ar + N_2 \ doping \\ \textbf{19^{th} - 28^{th} Jun. 2023 - 2^{nd} DLC sputtering test} \\ & Ar + N_2 \ doping \ (\% \ and \ P \ scan) \\ \textbf{25^{th} Place} \end{array}$

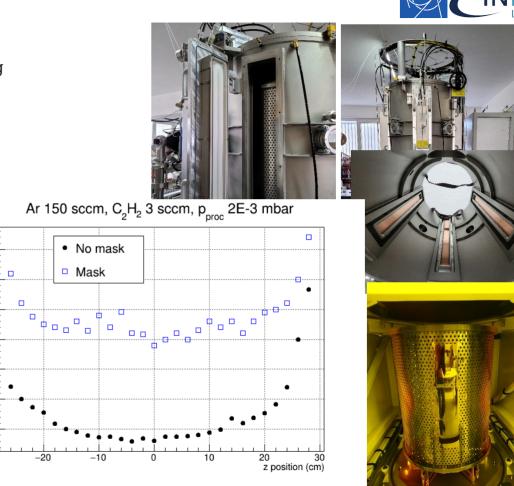
- $25^{\rm th}$ $29^{\rm th}$ Sep. 2023 $3^{\rm rd}$ DLC sputtering test
 - Ar + C_2H_2 doping
- $6^{\rm th}$ $10^{\rm th}$ Nov. 2023 $4^{\rm th}$ DLC sputtering test
 - Ar + C₂H₂ doping (uniformity test)

Technical features:

- Flexible substrates up to 1.7m×0.6m
- **Rigid** substrates up to 0.2m×0.6m

Five cooled target holders, arranged as two pairs face to face and one on the front, equipped with five shutters.

CID allows to **sputter** or **co-sputter different materials**, to create a coating layer by layer or an adjustable **gradient** in the coating.



Thanks to Rui, Serge, Givi and Gianfranco – more details in this talk

p (MΩ/D)

300

250

200

150

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2023 Stable and uniform DLC resistivity w/ Ar+C₂H₂ Ar 150 sccm, $C_{2}H_{2}$ 3 sccm, p_{proc} 2E-3 mbar No mask 350 Mask 300 250 200 150 100 -20-1010 20 z position (cm) Sputtering large foils!! 2024



p (MΩ/D)

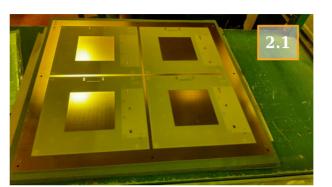
WP7.3.2: Mar.'23 ELTOS production – DLC patterning E

<u>Step 2:</u>

1) R/O PCB production

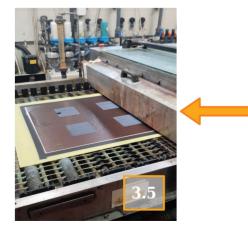
<u>Step 3:</u>

- 2) Photoresist lamination for DLC protection
- 3) Photoresist UV-**exposure**
- 4) Photoresist **development**
- 5) **DLC patterning** with brushing machine (@CERN different approach: JET-SCRUBBING)



DLC Kapton Cu



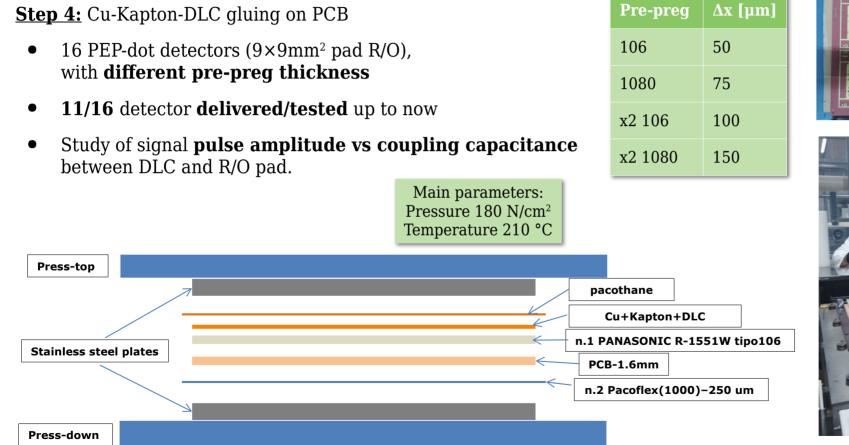






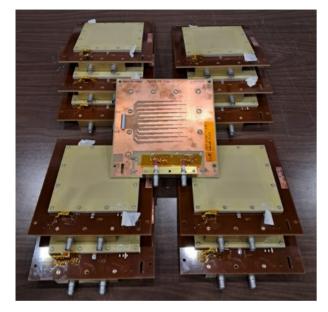
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WP7.3.2: Mar.'23 ELTOS production – DLC-foil gluing

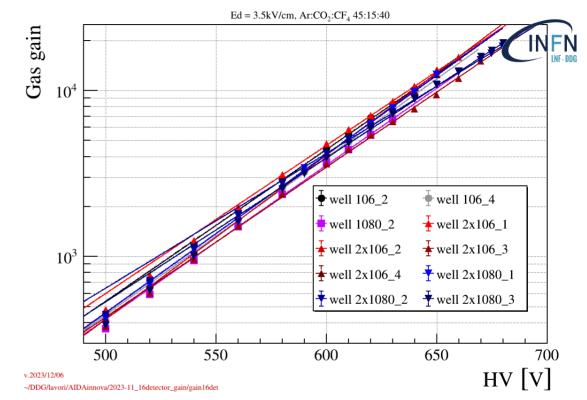




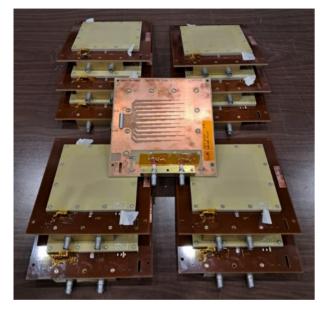




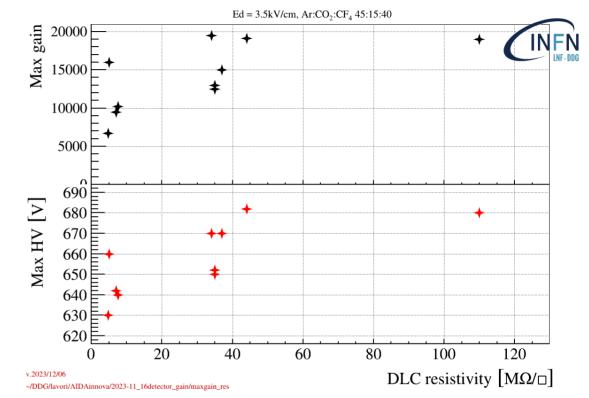
- 11/16 co-produced protos have been delivered and tested
- 10 are fine \rightarrow 90% yield
- 1 should be re-cleaned Waiting for the delivery of last 5 protos



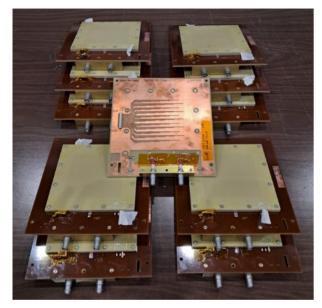
- Characterized with **X-ray gun** → **Gas gain** measurement
- Next step: measure of the pulse amplitude (APV25) vs Gas gain



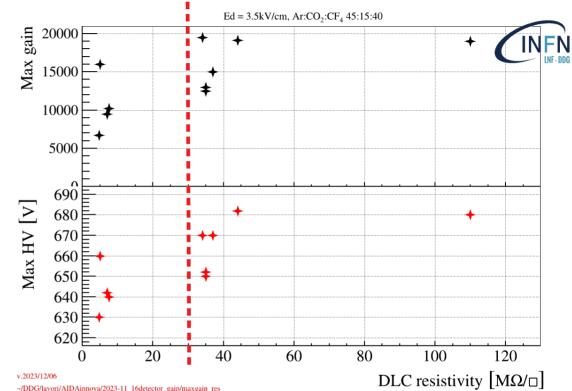
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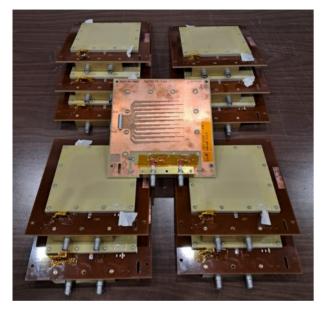
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Detector #	Prepreg type	DLC resistivity	Production status	Max HV/Gain	comments
106_1	1x 106		Cleaning		@ CERN
106_2	1x 106	7.5	Delivered	640/10000	
106_3	1x 106		Cleaning		@ CERN
106_4	1x 106	7	Delivered	640/9500	
1080_1	1x1080		Cleaning		@ CERN
1080_2	1x1080	4.8	Delivered	630/6700	
1080_3	1x1080	5	Delivered	n.a.	To be re-cleaned
1080_4	1x1080		Cleaning		@ CERN
2x106_1	2x106	35	Delivered	660/16000	
2x106_2	2x106	37	Delivered	650/13000	
2x106_3	2x106	35	Delivered	670/15000	
2x106_4	2x106	34	Delivered	650/12500	
2x1080_1	2x1080	33	Delivered	670/19500	
2x1080_2	2x1080	110	Delivered	680/19000	
2x1080_3	2x1080	44	Delivered	680/19000	
2x1080_4	2x1080		Cleaning		@ CERN

Status and plans – '23

- **Optimization** of high-rate µ-RWELL layout **10x10cm**² active area, 9x9mm² pad, **DOT DLC connection**
- Beam test (NA H8C, June, 2023) Groove DOT comparison (developed and tested in 2022) w/ APV25

Tests of **co-production ELTOS/CERN** and **DLC sputtering machine** @ CERN (tests will continue also in 2024)

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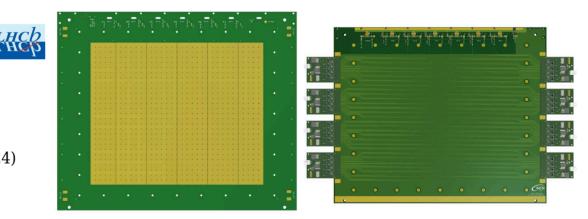
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Status and plans – '23, '24

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 - GIF++ irradiation test with μ -beam in collaboration with CERN gas group
 - **Integration of electronics based on the FATIC3 chip** (n.100 chip 32chs with multi-project run Jan. 2024).

M2R1 proto-0 (active area 250x300 mm²)

- Designed & discussed w/Rui (Oct./Nov. 2023)
- Delivery (March 2024)
- Characterization w/X-rays (April/May 2024)
- Cosmic rays stand w/APV25 (June Sept 2024)
- Test beam H8C w/FATIC3 (Oct.2024)



2024

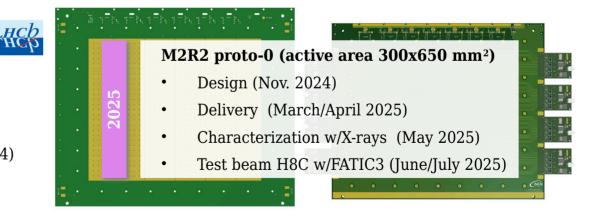
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Status and plans – '23, '24, '25

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2024

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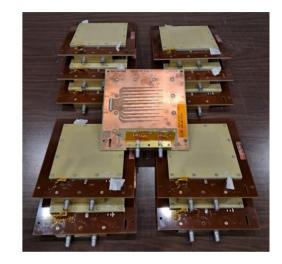
Summary

The TT of a part of μ -RWELLs construction steps to ELTOS Company, in close collaboration with the CERN MPT Workshop has been successfully completed (yield ~ 90%):

- Several construction steps performed by ELTOS
- Detector finalization (Kapton etching, electrical hot cleaning ...) done at CERN

The **R&D with CERN** on **high-rate layouts** will be **finalized within 2024**:

- **Design/optimization** of the high-rate layout → **PEP-Dot**, 97% geom. acceptance (**DONE**)
- Optimizing main detector parameters:
 - \circ ρ_s ≥ 30-40 MΩ/□ → maximizing the gas gain (almost DONE)
 - Optimization of prepreg thickness
 → maximizing collected signal (within 2023)
 - **Optimization of the amplification stage geometry** \rightarrow maximizing the gas gain (2024)
- Large size high-rate layout (M2R1 ...) construction/test (April Oct. 2024)



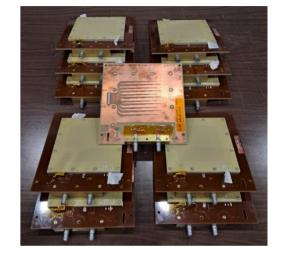
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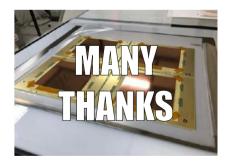
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Spare

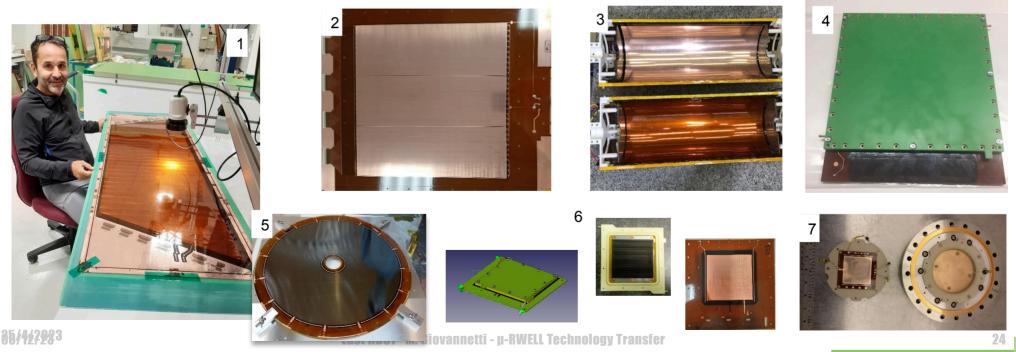
- G. Bencivenni et al., The micro-Resistive WELL detector: a compact spark-protected single amplification-stage MPGD, 2015 JINST 10 P02008
- G. Bencivenni et al., The µ-RWEL detector, 2017 JINST 12 C06027
- G. Bencivenni et al., Performance of µ-RWELL detector vs resistivity of the resistive stage, Nucl. Instrum. Meth. A 886 (2018) 36.
- G. Bencivenni et al., *The µ*-*RWELL layouts for high particle rate*, 2019 *JINST* **14** P05014
- G. Bencivenni et al., On the space resolution of the µ-RWELL, 2020 JINST 16 P08036
- A. Ochi et al., Carbon sputtering Technology for MPDG detectors, PoS(TIPP2014)351 (2014).



µ-RWELL technology spread

The $\mu\text{-RWELLs}$ are proposed in

- 1. CLAS12 @ JLAB: the upgrade of the muon spectrometer
- 2. X17 @ n_TOF EAR2: for the amplification stage of a TPC dedicated to the detection of the X17 boson
- 3. TACTIC @ YORK Univ.: radial TPC for detection of nuclear reactions with astrophysical significnace
- 4. Muon collider: hadron calorimeter
- 5. CMD3: uRWELL Disk for the upgrade of the tracking system
- 6. URANIA-V: a project funded by INFN-CSN5 for neutron detection,
- 7. UKRI: neutron detection with pressurized ³He-based gas mixtures



The High Rate layouts



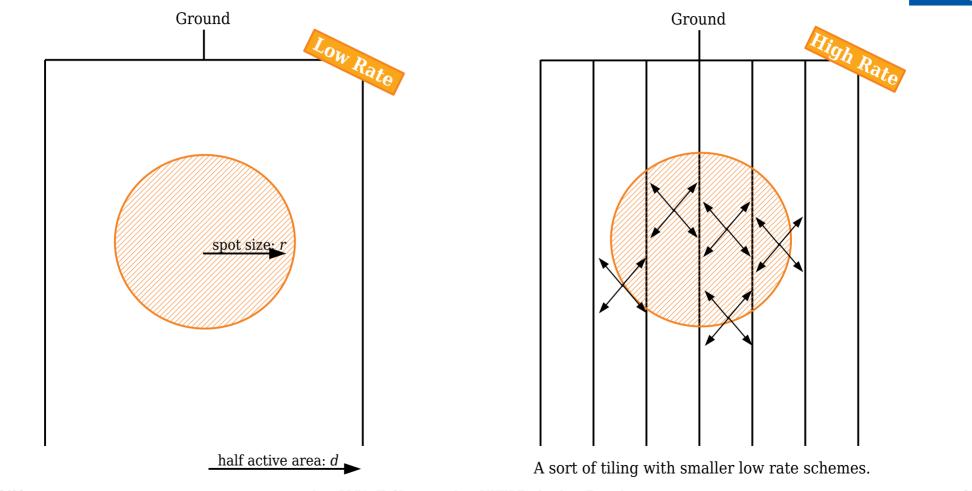
To overcome **the intrinsic limitation** of the Single Resistive layout with edge grounding the solution is to reduce as much as possible the paths towards the ground connection introducing high density а "grounding network" the on resistive stage of the detector.

Single Resistive Layout (SRL) Top Cu Grounding Metalized vias Readout DLC Pre-preg

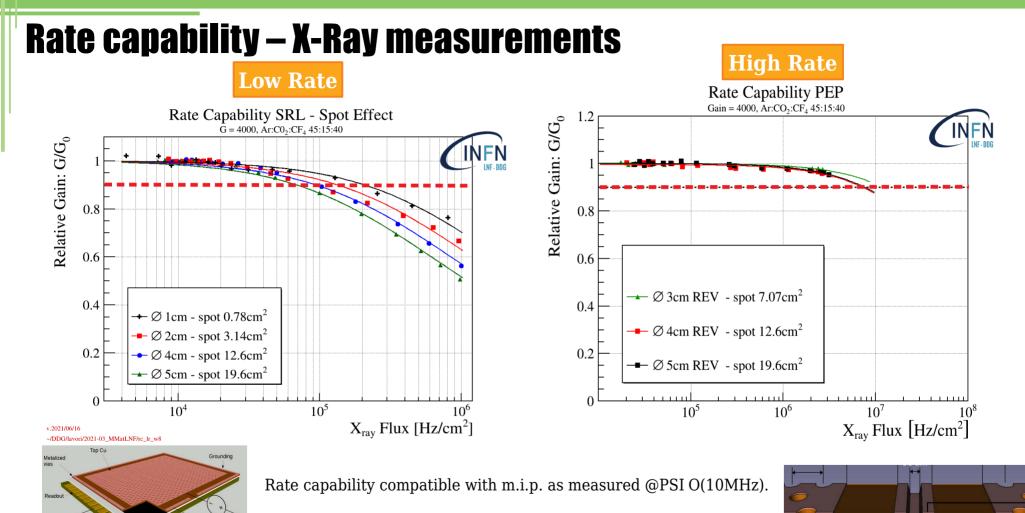
Different layouts with a "dense grounding network scheme" have been designed and implemented.

The High Rate layouts





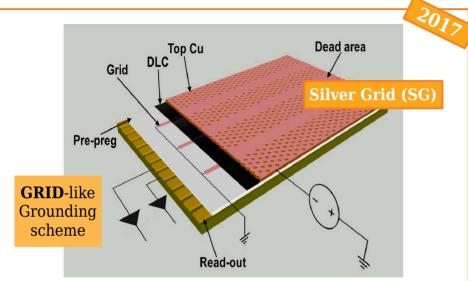
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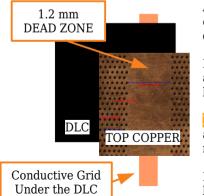


Different primary ionization \Rightarrow **Rate Cap**_{m.i.p.} = 3×Rate Cap_{X-ray}

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The High Rate layouts





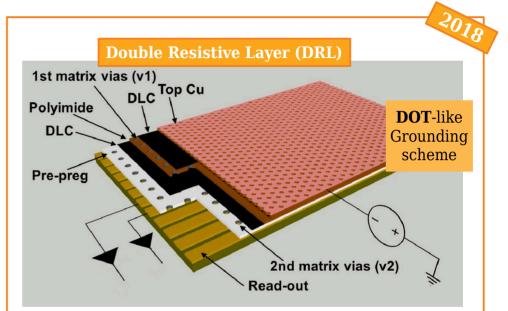
06/12/23

A conductive grid is patterned on the back of special DLC foils (DLC + Cu technology: delicate manufacturing process).

Necessity to introduce a **small DEAD AREA** above the grid, to avoid discharges (tuned to be 5% of the total area).

NOT SCALABLE to large size: distortions and alignment problems **during manufacturing**.

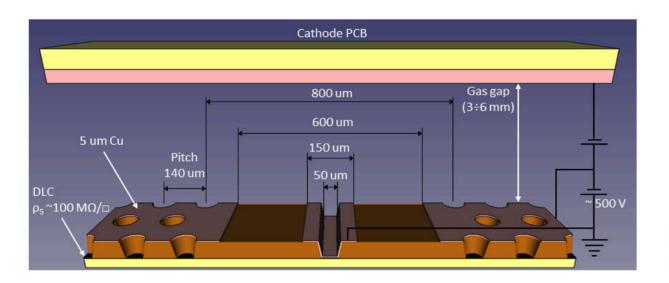
IS POSSIBLE to **check the resistance** of the layer after the detector is built



Based on a **3-D** current evacuation scheme: Two stacked resistive layer connected through a **matrix of conductive vias,** grounded through a further matrix of vias to the underlying readout electrodes.

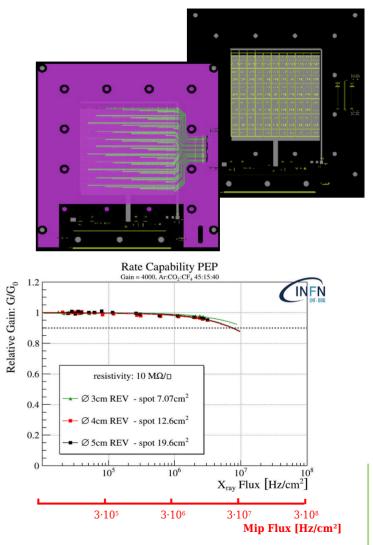
MORE COMPLEX to buid **than SG** but reliable (for now only 10x10 prototypes). **NOT POSSIBLE to check the resistance** of the two layers after the manifacture.

The HR layout – PEP Groove

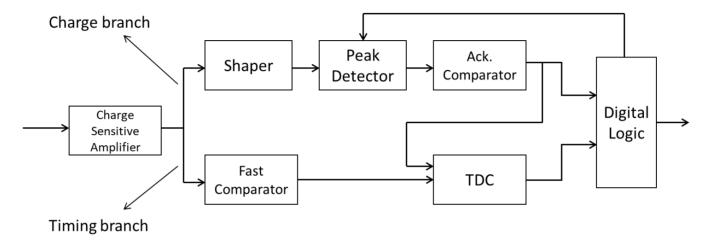


The **PEP** layout (Patterning – Etching – Plating) is the **state of art** of the **high rate** layout of the μ -RWELL developed **for LHCb**

- Single DLC layer
- **Grounding line from top** by kapton etching and plating (pitch down to 1/cm)
- No alignment problems
- High rate capability
- Scalable to large size (up to 1.2x0.5 m for the upgrade of CLAS12)



FATIC2 block diagram



Preamplifier features:

- CSA operation mode
- Input signal polarity: positive & negative
- Recovery time: adjustable

CSA mode:

- Programmable Gain: 10 mV/fC ÷ 50 mV/fC
- Peaking time: 25 ns, 50 ns, 75 ns, 100 ns

Timing branch:

- Measures the arrival time of the input signal
- ✓ Time jitter: 400 ps @ 1 fC & 15 pF (Fast Timing MPGD)

Charge branch:

- Acknowledgment of the input signal
- Charge measurement: dynamic range > 50 fC, programmable charge resolution